

2008 年度業績 — 節原 裕一

学術論文・解説記事

1. Y. Setsuhara, K. Takenaka, and A. Ebe, Large-Area Low-Damage Plasma Sources Driven by Multiple Low-Inductance-Antenna Modules for Next-Generation Flat-Panel Display Processes, *Surface and Coatings Technology*, 202, 5225-5229, 2008
2. Y. Setsuhara, K. Takenaka, A. Ebe and J. G. Han, Properties of Argon/Oxygen Mixture Plasmas Driven by Multiple Internal-Antenna Units, *Surface and Coatings Technology*, 202, 5230-5233, 2008
3. Y. Setsuhara, T. Sera, and K. Takenaka, Discharge Profiles of Internal-Antenna-Driven Inductively-Coupled Plasmas, *Surface and Coatings Technology*, 202, 5234-5237, 2008
4. Y. Setsuhara, D. Tsukiyama, K. Takenaka, Uniformity of 500-mm Cylindrical Plasma Source Sustained with Multiple Low-Inductance Antenna Units, *Surface and Coatings Technology*, 202, 5238-5241, 2008
5. K. Takenaka, H. Nakayama, Y. Setsuhara, H. Abe and K. Nogi, Modification of Yttrium-Iron-Oxide Nanoparticle Films Using Inductively-Coupled Plasma Annealing, *Surface and Coatings Technology*, 202, 5336-5338, 2008
6. J. Noma, H. Abe, M. Naito, K. Takenaka and Y. Setsuhara, Mechanical Milling of Nanoparticles under Electric Discharge, *Surface and Coatings Technology*, 202, 5347-5349, 2008
7. H. Kaki, E. Takahashi, T. Hayashi, K. Ogata, A. Ebe K. Takenaka and Y. Setsuhara, Interface structures of microcrystalline silicon films deposited with inductively coupled plasmas using internal low-inductance antenna units, *Surface and Coatings Technology*, 202, 5672-5675, 2008
8. K. Takenaka, Y. Setsuhara, K. Nishisaka and A. Ebe, Characterization of Ion Energy Distribution in Inductively-Coupled Argon Plasmas Sustained with Multiple Internal Antenna Units, *Japanese Journal of Applied Physics*, 47, 6900-6902, 2008
9. Y. Setsuhara, D. Tsukiyama, K. Takenaka and K. Ono, Simulation-Aided Designing of Meter-Scale Large-Area Plasma Source with Multiple Low-Inductance Antenna Modules, *Japanese Journal of Applied Physics*, 47, 6903-6906, 2008
10. Jaroslav Vlcek, Stanislav Hreben, Jiri Kalas, Jiri Capek, Petr Zeman, Radomir Cerstvy, Vratislav Perina and Yuichi Setsuhara, Magnetron sputtered Si-B-C-N films with high oxidation resistance and thermal stability in air at temperatures above 1500°C, *J. Vac. Sci. Technol. A*, 26, 1101-1108, 2008
11. Jiro Okado, Ken Okada, Asahiko Ishiyama, Yuichi Setsuhara, and Kosuke Takenaka, Corrosion Resistance of Plasma-Oxidized Stainless Steel, *Surface and Coatings Technology*, 202, 5595-5598, 2008

受賞

1. Yuichi Setsuhara, Invited Presentation Award, Interfinish 2008 World Interfinish Congress & Exposition, 2008.6.18

特許権などの知的財産権

1. 節原裕一、他 3 名、特願 2008-117732、出願年月日：2008/4/28
2. 節原裕一、他 3 名、特願 2008-117733、出願年月日：2008/4/28
3. 節原裕一、他 3 名、特願 2008-122898、出願年月日：2008/5/9
4. 節原裕一、他 2 名、特願 2008-218946、出願年月日：2008/8/28